August 1969

NASA TECH BRIEF



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Semiautomatic Inspection of Microfilm Records

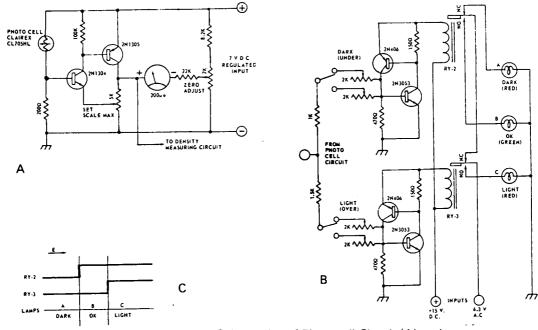


Fig. 1. MARK 1: Schematics of Photocell Circuit (A) and Density-Measuring Circuit (B), and Logic Diagram (C)

The problem:

Microfilm in a 35mm format is the industry standard for recording engineering data and other documentation for long-term storage and retrieval. Microfilm records used by the government are controlled by Specification MIL-STD-108. This specification prescribes image size and position tolerances, resolution requirements, and density restrictions.

Heretofore, microfilm inspection has been done manually, using an individual microscope, a densitometer, a light box, and hand-cranked reels. This method is not only time-consuming but it is sometimes of questionable quality since subjective judgment of the inspection personnel is a major factor.

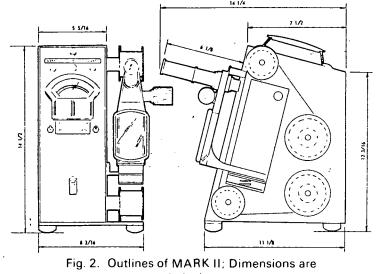
The solution:

Inasmuch as deficiencies in microfilm quality are undetected by this nonuniformity of inspection apparatus it follows that these deficiencies can be alleviated by providing a semiautomatic-type inspection machine for this purpose. Accordingly, two working models were designed and constructed by the support contractor to the MSFC Management Services Office. Improvements in reliability and ease of operation

(continued overleaf)

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in inches.

were made in the second prototype identified as MARK II.

3. Improved quality through elimination of scratches, finger marks, etc.

How it's done:

The microfilm inspector utilizes motor-driven film reels with a means for precisely positioning the microfilm image for inspection. Film density is measured by means of a photoelectric cell and solid-state electronic circuit. Over and under tolerances are preset according to specification. As the film is inspected, go-no-go indicator lights advise the operator of the film status. In addition to the lights, a densitometer provides specific values for film density. These are recorded to back up the film-inspection report.

Resolution of the photographic image on the film is determined by a microscope which is an integral part of the machine. Image size and position are also determined by a built-in optical device.

Principal advantages of the microfilm inspector are:

1. Uniformity of inspection method.

2. Increased speed of inspection.

Note:

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and Technical Information Springfield, Virginia 22151 Price \$3.00 Reference: TSP69-10301

Patent status:

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> Source: E. L. Klein of **RCA** Service Company under contract to Marshall Space Flight Center (MFS-20240)

> > Category 02